

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490

Filed: January 26, 2001

Group Art Unit: 2882

Examiner: C. Kao

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR,
SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND
SEMICONDUCTOR DEVICE

THE COMMISSIONER FOR PATENTS AND TRADEMARKS
Washington, DC 20231

Dear Sir:

Transmitted herewith is an Amendment in the above identified application.

☐

No additional fee is required.

☐

Small entity status of this application under 37 CFR 1.9 and 1.27 has been established by a verified statement previously submitted.

☐

A verified statement to establish small entity status under 37 CFR 1.9 and 1.27 is enclosed.

Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	49	45	4	\$18.00 =	\$72.00
Independent Claims	6	6	0	\$84.00 =	\$0.00
Multiple claims newly presented					\$0.00
Fee for extension of time					\$0.00
					\$0.00
Total of Above Calculations					\$72.00

☒ Please charge my Deposit Account No. 500417 in the amount of \$72.00. An additional copy of this transmittal sheet is submitted herewith.

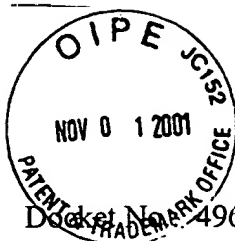
☒ The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

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Docket No. 49657-961

PATENT

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AMENDMENT

Commissioner for Patents
Washington, DC 20231

Sir:

In response to the Office Action dated August 1, 2001, having a three-month shortened statutory period for response set to expire on November 1, 2001, reconsideration of the above-identified application is respectfully requested in view of the following amendment and remarks.

IN THE CLAIMS

Please cancel claim 19.

Please amend claims 1, 16, 24, 40 and 42 to read as follows:

1. An X-ray exposure apparatus comprising an X-ray mirror containing a material having an absorption edge only in a wavelength region other than 0.45 nm

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